

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

~~In re~~ Application of:

YASUHISA INAO, ET AL.

Application No.: 10/663,691

Filed: September 17, 2003

For: MASK, EXPOSURE
APPARATUS, AND
EXPOSURE METHOD

December 18, 2003

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the documents listed below and on the enclosed Form PTO-1449. Copies of documents (2) and (3) are also enclosed, along with an English-language abstract for document (2).

- (1) U.S. Patent No. 6,171,739
- (2) Japan 2000-112116
- (3) "Sub-diffraction-limited patterning using evanescent near-field optical lithography," M.M. Alkaisi et al., *Applied Physics Letters* (1999), Vol. 75, No. 22, pp. 3560-3562.


These documents were cited on page 8 of the subject application, and might be deemed relevant for the reasons noted therein.

A copy of the newly cited U.S. Patent Application is not being provided in accordance to the Pre-Official Gazette Notice dated, July 11, 2003, entitled "Information Disclosure Statements Filed Without Copies Of U.S. Patents and Published Applications in Patent Applications filed after June 30, 2003.

Inasmuch as the subject application has not yet received a first Office Action, it is believed that this Information Disclosure Statement is timely. See 37 C.F.R. 1.97(b)(3). Accordingly, the Examiner is urged to study this information in its entirety and to form an independent determination of the materiality of the information to the claimed invention. Additionally, the Examiner is requested to indicate that this information has been considered by initialing the appropriate portion of the Form PTO-1449.

Applicants' undersigned attorney may be reached in our Costa Mesa, California office by telephone at (714) 540-8700. All correspondence should continue to be directed to our address given below.

Respectfully submitted,


Attorney for Applicants
Registration No. 54,336

FITZPATRICK, CELLA, HARPER & SCINTO
30 Rockefeller Plaza
New York, New York 10112-3800
Facsimile: (212) 218-2200

